



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner Shamim Ahmed
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

RECEIVED
NOV 03 2003
GROUP 1700

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

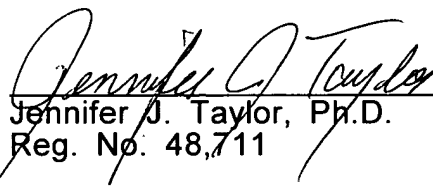
References -- See Attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 10-27-2003

By:


Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

EL079977829

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-1106SERIAL NO.
09/360,292LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)

APPLICANT: Sujit Sharan et al.

FILING DATE
July 22, 1999GROUP
1746

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,051,503	04-2000	Bhardwaj et al.			
	AB	5,880,005	03-1999	Tsai et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

RECEIVED

NOV 03 2003

GROUP 1700

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.